

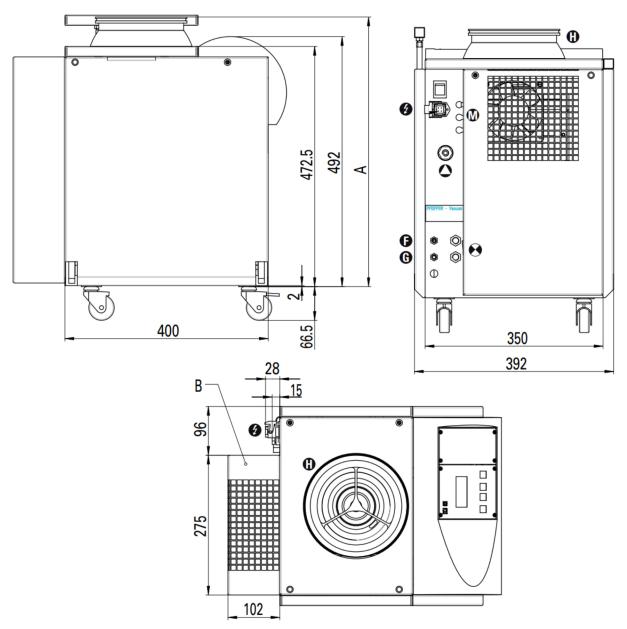
Pfeiffer HiCube 300 Classic Technical Specifications

		HiCube 300 Classic	
Flange (in)		DN 100 ISO-K	DN 100 CF-F
Pumping speed for Nitrogen N ₂	l/s	260	260
Ultimate pressure			
with Rotary vane pump DuoLine	mbar	< 1 · 10 ⁻⁷	< 5 · 10 ⁻¹⁰
with Diaphragm pump MVP	mbar	< 1 · 10 ⁻⁷	< 1 · 10-8
Pumping speed backing pump at 50 Hz			
Diaphragm pump MVP 015	m³/h	_	-
Diaphragm pump MVP 040	m³/h	2.3	2.3
Diaphragm pump MVP 070	m³/h	3.8	3.8
Rotary vane pump Duo 2.5	m³/h	2.5	2.5
Rotary vane pump Duo 5 M	m³/h	5	5
Weight pumping station: ¹⁾			
with Diaphragm pump MVP 015	kg	_	-
with Diaphragm pump MVP 040	kg	41.2	43.2
with Diaphragm pump MVP 070	kg	46.2	48.2
with Rotary vane pump Duo 2.5	kg	40.3	42.3
with Rotary vane pump Duo 5 M	kg	48.8	50.8
Power consumption			
with Diaphragm pump MVP 015	W	_	_
with Diaphragm pump MVP 040	W	480	480
with Diaphragm pump MVP 070	W	550	550
with Rotary vane pump Duo 2.5	W	460	460
with Rotary vane pump Duo 5 M	W	550	550

Ultimate pressure in a measuring dome 48 hours after bake-out, can be attained only with metallic seal of the high vacuum flange. (Ultimate pressure with elastomer seal (standard, not bakeable): $< 1 \cdot 10^{-7}$ mbar.) ¹ without fore-vacuum safety valve



Pfeiffer HiCube 300 Classic Dimensions



Dimensions	HiCube 300 Classic	HiCube 300 Classic
Flange (in)	DN 100 ISO-K	DN 100 CF-F
A	580 mm	592 mm
В	102 mm only with DUO 5	

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Pfeiffer HiCube 300 Classic Features & Benefits

- floor standing, compact pumping station
- easy data collection & analysis
- optimal combination of HiPace turbo pump & backing pump
- modular design affords simple customization for application
- service friendly due to accessibility of individual components
- integrated drive electronics
- plug & play no installation or cabling required
- robust engineering makes for long service life
- optional forevacuum safety valve prevents venting in power failure
- direct connection of vacuum gauges possible

Applications

- research & development accelerators analysis & surface physics
- vacuum process technology general vacuum applications

